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**Surface chemical analysis — Auger
electron spectroscopy — Reporting of
methods used for charge control and
charge correction**

*Analyse chimique des surfaces — Spectroscopie des électrons
Auger — Indication des méthodes mises en œuvre pour le contrôle et la
correction de la charge*



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Contents

Contents	Page
Foreword	iv
Introduction.....	v
1 Scope	1
2 Normative references.....	1
3 Terms and definitions	1
4 Symbols and abbreviated terms	1
5 Apparatus	2
5.1 Charge-control technique.....	2
5.2 Special apparatus.....	2
5.3 Specimen mounting and preparation.....	3
5.4 Instrument calibration.....	3
6 Reporting of information related to charge control.....	3
6.1 Methods of charge control	3
6.2 Reasons for needing charge control and choice of method	3
6.3 Specimen information	3
6.3.1 Specimen form.....	3
6.3.2 Specimen dimensions.....	4
6.3.3 Specimen-mounting methods	4
6.3.4 Specimen treatment prior to or during analysis	4
6.4 Values of experimental parameters.....	4
6.5 Information on the effectiveness of methods of charge control	4
7 Reporting of method(s) used for charge correction and the value of that correction.....	5
7.1 Methods of charge correction	5
7.2 Approach	5
7.3 Value of correction energy	5
Annex A (informative) Description of methods of charge control for Auger electron spectroscopy	6
A.1 Introduction.....	6
A.2 Hierarchical table of methods for reducing charging.....	7
A.3 Methods for minimizing charging during AES	9
A.3.1 Introduction.....	9
A.3.2 Decreasing specimen resistivity.....	9
A.3.3 Decreasing the insulator thickness (or effective insulator thickness)	9
A.3.4 Reducing the current density, limiting primary-electron dose and using additional current sources	11
A.3.5 Optimizing the total secondary-electron emission yield.....	12
A.4 Considerations for highly non-uniform specimens, fibres and particles and the use of sputter depth profiling	14
A.4.1 Introduction.....	14
A.4.2 Dealing with rough surfaces, particles, fibres and other non-uniform specimens	14
A.4.3 Sputter depth profiling	14
A.5 General considerations concerning charge build-up during AES	15
A.5.1 Introduction.....	15
A.5.2 Resistivity, capacitance and surface potential	15
A.5.3 Total secondary-electron yield and surface potential	17
A.5.4 Charge transport and accumulation below the surface, time-dependent charge accumulation and specimen damage.....	20
Bibliography.....	21